

2814



## PATENT

Case Docket No. ASMEX.367A

Date: September 26, 2003

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Michael A. Todd  
 Appl. No. : 10/074,534  
 Filed : February 11, 2002  
 For : PROCESS FOR DEPOSITION  
 OF SEMICONDUCTOR FILMS  
 Examiner : Shrivinas H. Rao  
 Group Art Unit : 2814

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

September 26, 2003

(Date)

*Joseph J. Mallon*  
 Joseph J. Mallon, Reg. No. 39,287

## TRANSMITTAL LETTER

Commissioner for Patents  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application are:

- (X) An Information Disclosure Statement.
- (X) A PTO Form 1449 with one (1) references.
- (X) The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment, to Account No. 11-1410.
- (X) Return prepaid postcard.

*Joseph J. Mallon*  
 Joseph J. Mallon  
 Registration No. 39,287  
 Attorney of Record  
 Customer No. 20,995  
 (619) 235-8550



# INFORMATION DISCLOSURE STATEMENT

Applicant : Michael A. Todd  
 App. No. : 10/074,534  
 Filed : February 11, 2002  
 For : PROCESS FOR DEPOSITION OF  
 SEMICONDUCTOR FILMS  
 Examiner : Shrivinas H. Rao  
 Group Art Unit : 2814

Commissioner for Patents  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing one (1) reference that is also enclosed.

This Information Disclosure Statement is being filed before the receipt of a first Office Action on the merits, and presumably no fee is required in accordance with 37 C.F.R. § 1.97(b)(3). If a first Office Action on the merits was mailed before the mailing date of this Statement, the Commissioner is authorized to charge the fee set forth in 37 C.F.R. § 1.17(p) to Deposit Account No. 11-1410.

Respectfully submitted,  
 KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 9/26/03

By: Joseph J. Mallon  
 Joseph J. Mallon  
 Registration No. 39,287  
 Attorney of Record  
 Customer No. 20,995  
 (619) 235-8550



FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.  
ASMEX 367AAPPLICATION NO.  
10/074,534INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT

(USE SEVERAL SHEETS IF NECESSARY)

APPLICANT  
Michael A. ToddFILING DATE  
February 11, 2002GROUP  
2814

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

EXAMINER  
INITIAL

## OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

Todd, Michael A. et al., "Deposition of Si<sub>1-x</sub>Ge<sub>x</sub> Films for Gate Electrode Applications Using a Novel Approach,"  
ICSI3, The SiGe Conference; Santa Fe, NM, March 2003

S:\DOCS\JOM\JOM-5265.DOC:092603

EXAMINER

DATE CONSIDERED

\*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT  
IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.